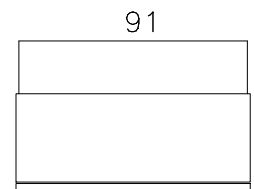


2000 micron



CS-114 Calibration Substrate Key

(all structures for probes with one ground)

Location #	Description	Coordinates (X,Y in micrometers)
00	open pads (600 to 1250 micrometer pitch)	
01	50 ohm loads (600 to 1250 micrometer pitch)	
10	6600 micrometer 50 ohm coplanar line (250 to 600 micrometer pitch)	(0,-4000) from 40 for left probe
20	shorting bars (600 to 1250 micrometer pitch)	
21	550 micrometer long 50 ohm line (600 to 1250 micrometer pitch)	
30	right angle alignment structure (pair) (250 to 600 micrometer pitch)	
31	right angle open pads for G,S probes (pair) (250 to 600 micrometer pitch)	
32	right angle shorting bars for G,S probes (pair) (250 to 600 micrometer pitch)	
33	right angle load for G,S probes (pair) (250 to 600 micrometer pitch)	
34	right angle 50 ohm line for G,S probes (250 to 600 micrometer pitch)	
35	25 ohm and 100 ohm loads (250 to 600 micrometer pitch)	
40	350 micrometer spacing alignment structure #1	
41	350 micrometer spacing alignment structure #2	(1700,0) from 40
42	350 micrometer spacing alignment structure #3	(3400,0) from 40
43	350 micrometer spacing alignment structure #4	(5100,0) from 40
50	open pads for non mirror image probes (pair) (250 to 600 micrometer pitch)	(-1700,2000) from 40
51	open pads (pair) (250 to 600 micrometer pitch)	(0,2000) from 40
52	open pads (pair) (250 to 600 micrometer pitch)	(1700,2000) from 40
53	open pads (pair) (250 to 600 micrometer pitch)	(3400,2000) from 40
54	open pads (pair) (250 to 600 micrometer pitch)	(5100,2000) from 40
55	open pads (pair) (250 to 600 micrometer pitch)	(6800,2000) from 40
56	open pads (pair) (250 to 600 micrometer pitch)	(8500,2000) from 40
60	shorting bar for non mirror image probes (pair) (250 to 600 micrometer pitch)	(-1700,4000) from 40
61	shorting bar (pair) (250 to 600 micrometer pitch)	(0,4000) from 40
62	shorting bar (pair) (250 to 600 micrometer pitch)	(1700,4000) from 40
63	shorting bar (pair) (250 to 600 micrometer pitch)	(3400,4000) from 40
64	shorting bar (pair) (250 to 600 micrometer pitch)	(5100,4000) from 40
65	shorting bar (pair) (250 to 600 micrometer pitch)	(6800,4000) from 40
66	shorting bar (pair) (250 to 600 micrometer pitch)	(8500,4000) from 40
70	50 ohm loads for non mirror image probes (pair) (250 to 600 micrometer pitch)	(-1700,6000) from 40
71	50 ohm loads (pair) (250 to 600 micrometer pitch)	(0,6000) from 40
72	50 ohm loads (pair) (250 to 600 micrometer pitch)	(1700,6000) from 40
73	50 ohm loads (pair) (250 to 600 micrometer pitch)	(3400,6000) from 40
74	50 ohm loads (pair) (250 to 600 micrometer pitch)	(5100,6000) from 40
75	50 ohm loads (pair) (250 to 600 micrometer pitch)	(6800,6000) from 40
76	50 ohm loads (pair) (250 to 600 micrometer pitch)	(8100,6000) from 40
80	50 ohm coplanar line for non mirror image probes, 550 um long (250 to 600 micrometer pitch)	(-1700,8000) from 40
81	550 micrometer long line (250 to 600 micrometer pitch)	(0,8000) from 40
82	550 micrometer long line (250 to 600 micrometer pitch)	(1700,8000) from 40
83	550 micrometer long line (250 to 600 micrometer pitch)	(3400,8000) from 40
84	550 micrometer long line (250 to 600 micrometer pitch)	(5100,8000) from 40
85	550 micrometer long line (250 to 600 micrometer pitch)	(6800,8000) from 40
86	550 micrometer long line (250 to 600 micrometer pitch)	(8100,8000) from 40
90	6600 micrometer long line (250 to 600 micrometer pitch)	(-2200,11000) from 40 for left probe
91	2000 micrometer long line (250 to 600 micrometer pitch)	(7050,11000) from 40 for left probe

Table 1